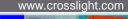


3D Simulation of CMOS Image Sensor

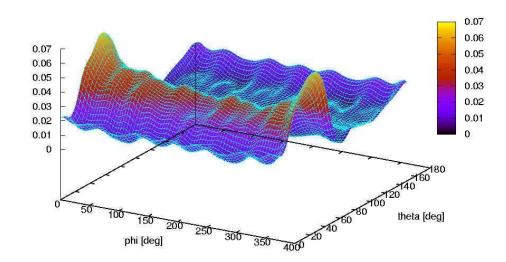
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Outline

- Introduction to Crosslight TCAD
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A Glimpse

- A leading TCAD provider since 1993
- The world's No.1 TCAD simulator for optics and photonics application
- The world's first commercialized TCAD for Laser Diode
- Customer list extends to hundreds of companies, research institutions and universities world wide.
- Originally Crosslight is a spin-off of the National Research Council of Canada and later licensed the Suprem 4 from Stanford University to build CSuprem





Crosslight Global Offices





Vancouver Headquarter







Shanghai Office

Japan Office





Taiwan Distributor



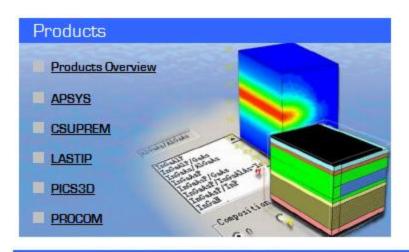
China Distributor

India and
Southeast Asia
Distributor

Korea Distributor



Main Product Portfolio and Typical Applications





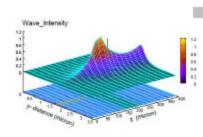
Optics and Photonics Applications

Solar Cells

Solar Cell (Thin-film)
Solar Cell (multi-junction)
Solar Cell (crystalline/poly)

Photo Detectors

Avalanche Photo Detectors CMOS Image Sensor QWIP



LEDs

RC LED
Organic LED (OLED)
White OLED (WOLED)
Quantum Dot LED
Photonic Crystal LED
Superluminescent LED
MOCVD Growth

Laser Diodes

Quantum Cascade Laser
Edge Emitting Laser
VCSEL
Quantum Dot Laser

Microelectronics Applications

CMOS

Nano-MOSFETs Strained Silicon CMOS Process

HEMT

GaN HEMT GaAs HEMT MOCVD Growth

Power Devices

BJT LDMOS Superjunction LDMOS Interconnect

MEMS (3D)

Advanced Physics

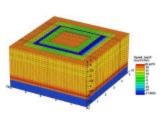
Advanced Device Physics

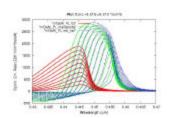
Quantum Drift and Diffusion

Intraband Quantum Tunneling Through Heterojunctions

Crystal orientation on Optical property of GaN Devices

Manybody, Exciton and inhomogeneous Broadening Effects



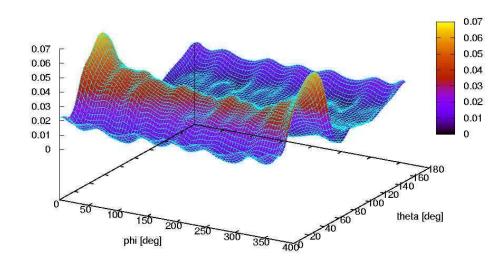






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About3D Simulation

Why 3D?

▲ Device is 3D in nature, lot's of devices need 3D simulation for better accuracy. For example, CMOS Image Sensor, Superjunction LDMOS, metal interconnect, etc.

Do you need 3D Simulation?

- Does your device have third (z) dimension variations?
- ▲ Do you want to exam some peripheral behavior of the device, like fringe current at the corner of race-track shaped gate?
- ▲ Does your device have a special shape from top down view? (like CMOS Image Sensor, or HEXFET)?

Challenges for 3D Simulation:

- Extremely time consuming. Believe or not, traditional 3d simulation time may be longer than real process time for large power semiconductor devices.
- Difficult to build the structure and optimize the mesh.

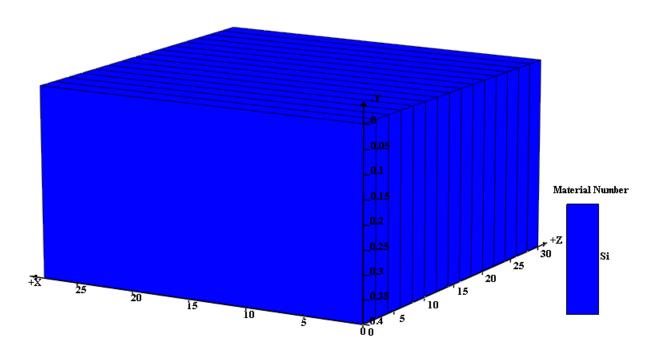




Crosslight's Approach of 3D Simulation

Stacked3D

Stacked3D Example:

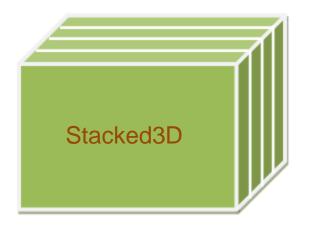


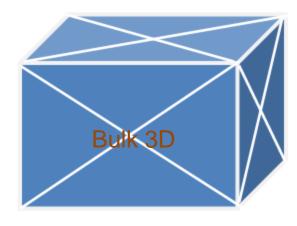


Advantages of Stacked3D

Stacked3D Advantages

- Highly Efficient, generally less mesh points required, mesh density can easily be varied
- Easy to build: It starts from 2D planes
- Easy to optimize mesh. The mesh can be optimized for individual planes
- Increased 3D success rate from successful 2D simulation
- Directly extract 2D planes and 2D simulation



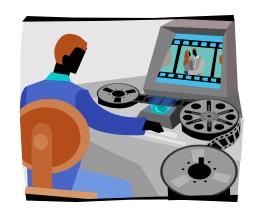




Introducing the New MaskEditorTM and SemiCrafterTM

What's MaskEditor/SemiCrafter?

▲ A powerful 3D mask editing tool for 3D simulation



What are the Applications?

- MaskEditor is a general purpose layout tool
- Works seamlessly with CSuprem to create 3D structure for virtually all types of semiconductor devices, like MOSFET, BJT, LED, etc.

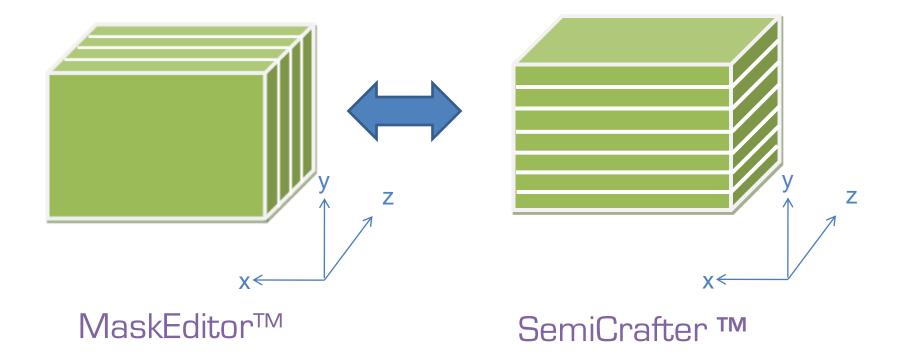
What are the Basic Functions of MaskEditor/SemiCrafter?

- Creates device layout files in GDSII format from scratch (Beta).
- Auto cutting and generate masks needed for 3D Csuprem process simulation.





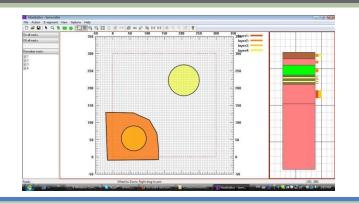
The Difference between MaskEditor™ and SemiCrafter™

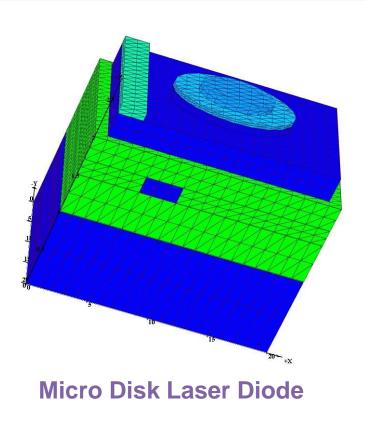


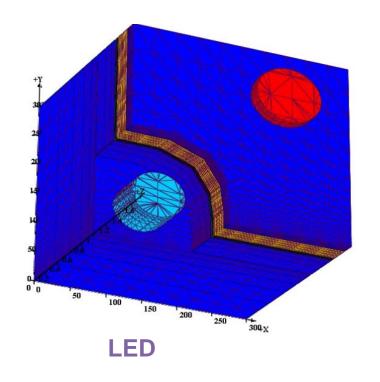


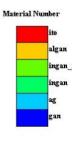
Examples of SemiCrafter™

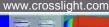
LED and Micro Disk Laser Diode Examples





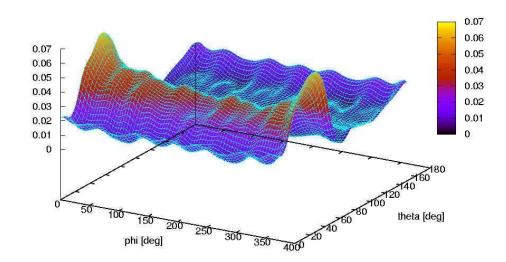






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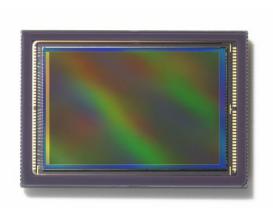
The Application of CMOS Image Sensor



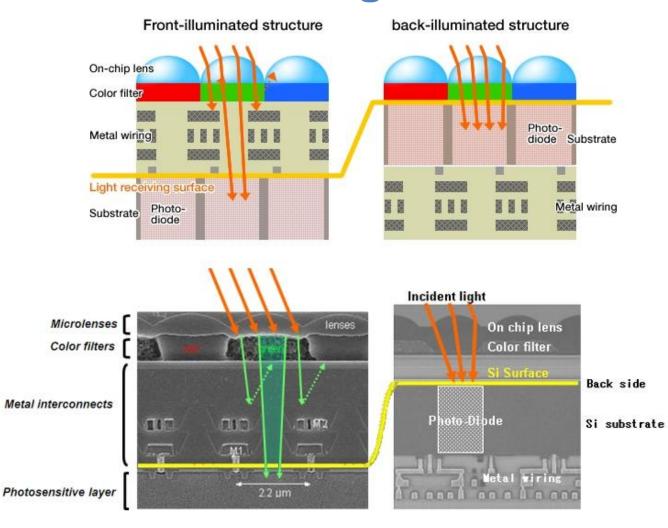




Introduction To CMOS Image Sensor



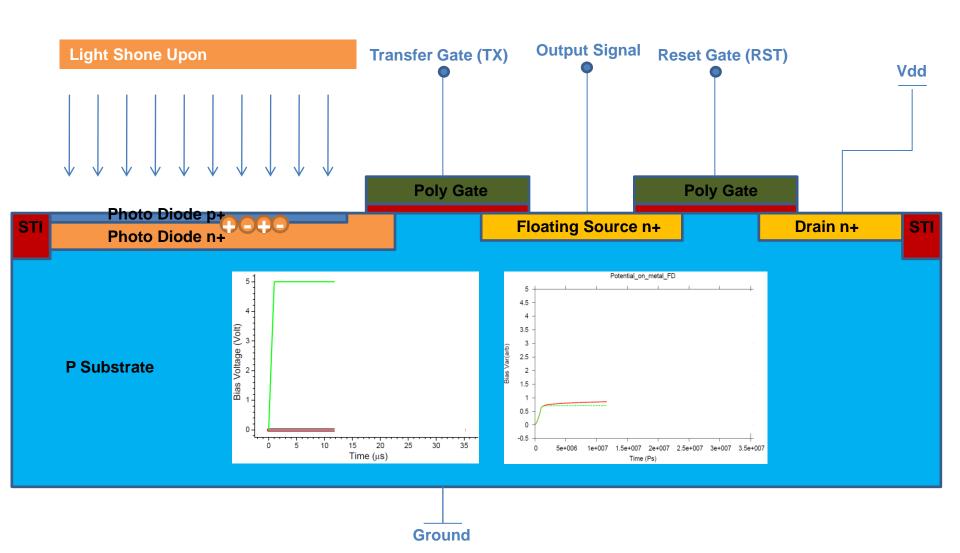
Canon CMOS Image Sensor



Source: http://www.i-micronews.com/lectureArticle.asp?id=1607
http://www.usa.canon.com/dlc/controller?act=GetArticleAct&articleID=246

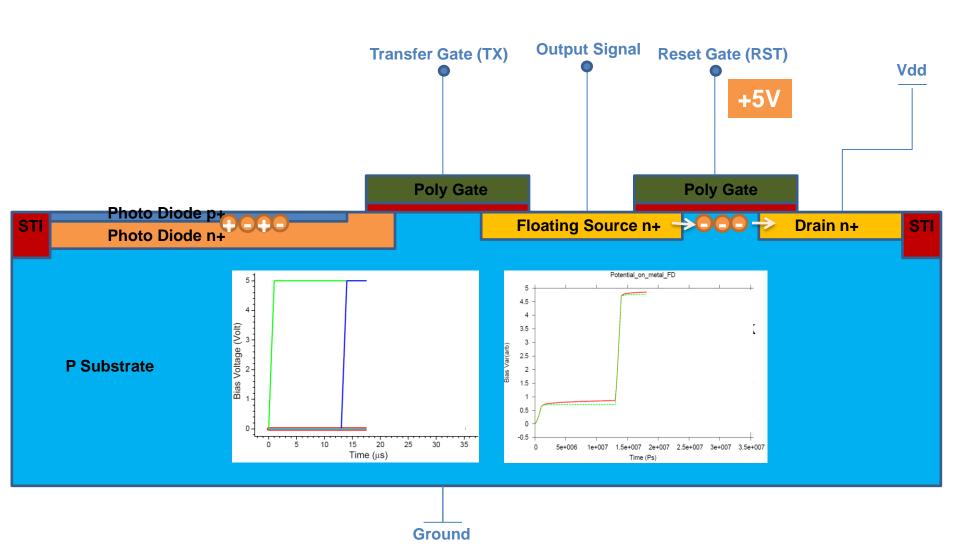


Simplified Simulation Structure and Bias



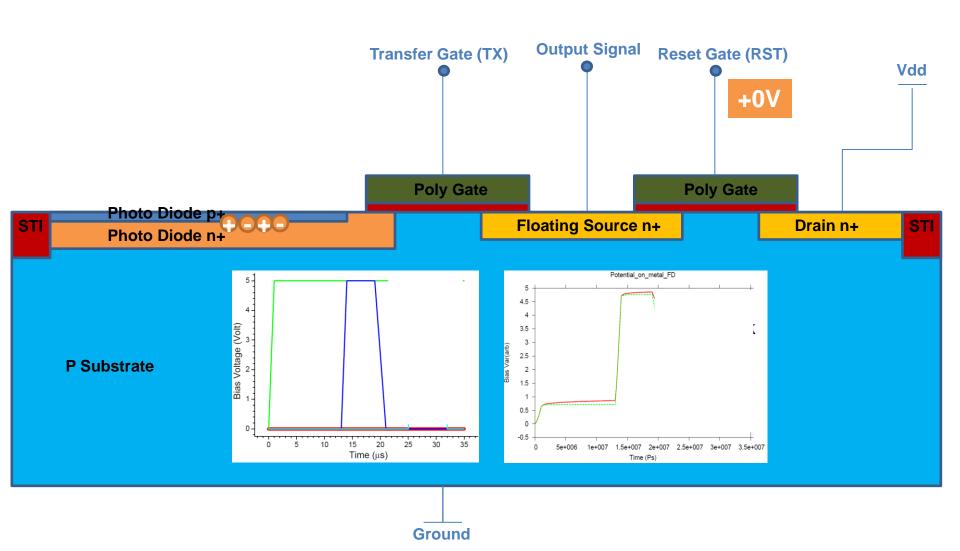


Reset Gate (RST) Turned On



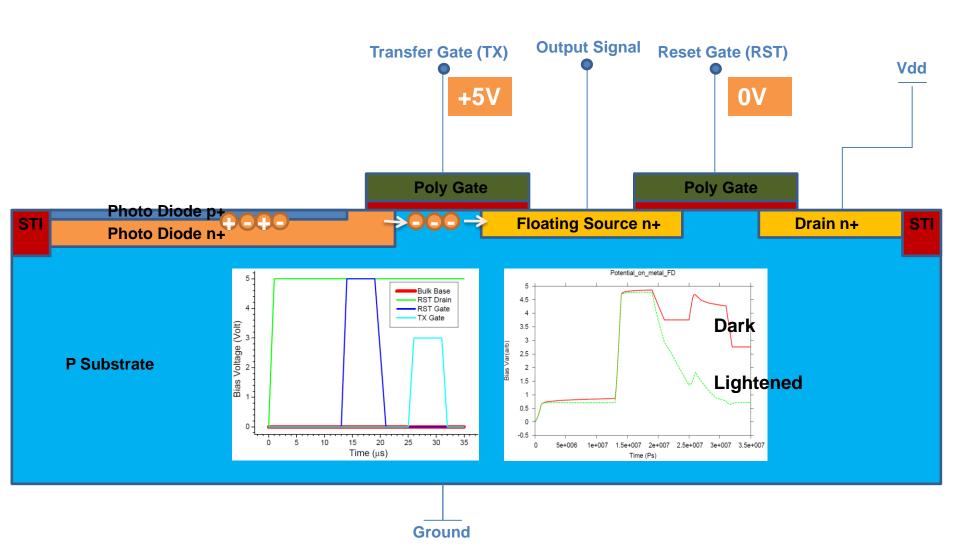


Reset Gate (RST) Turned Off





Transfer Gate (TX) Turned On

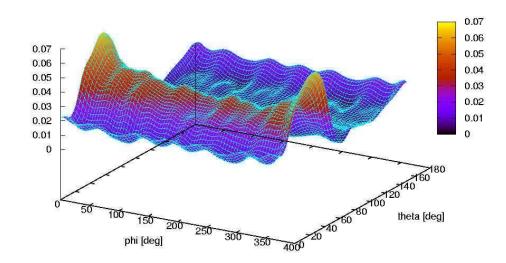


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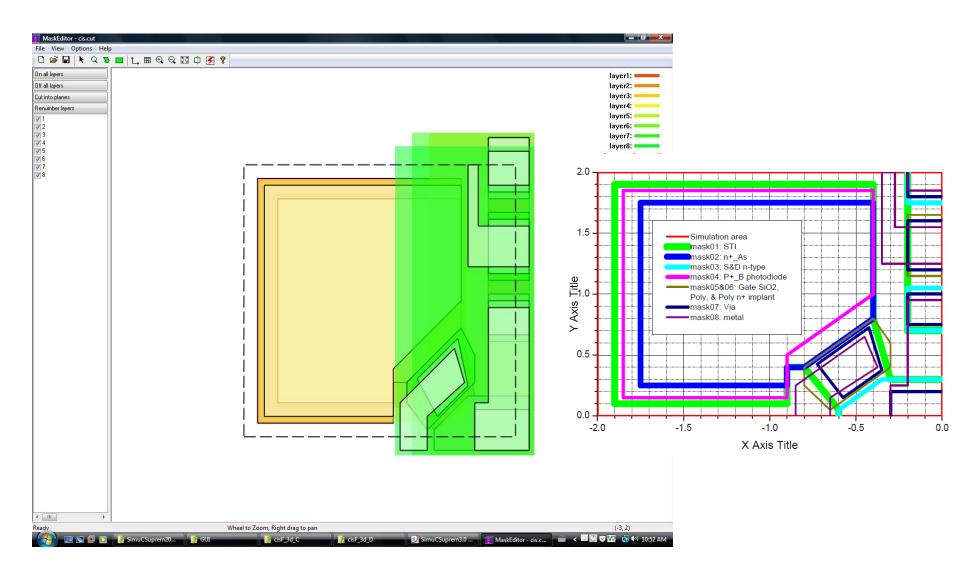


Overview of Fake CMOS Image Sensor Process

Step4: p+ Step7: Step1:STI implant for Contacts **Formation** PhotoDiode Define Step5: Gate Step2: n+ Step8: Metal implant for Oxide growth 1 Formation PhotoDiode and etch Step3: Step6: Gate Source-Drain Poly deposit Step9: Lens and etch n+ implant

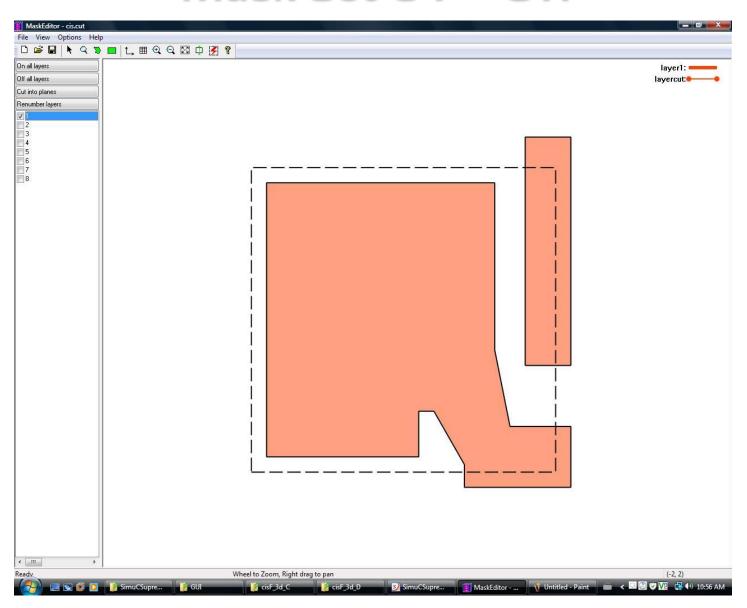


Mask Sets





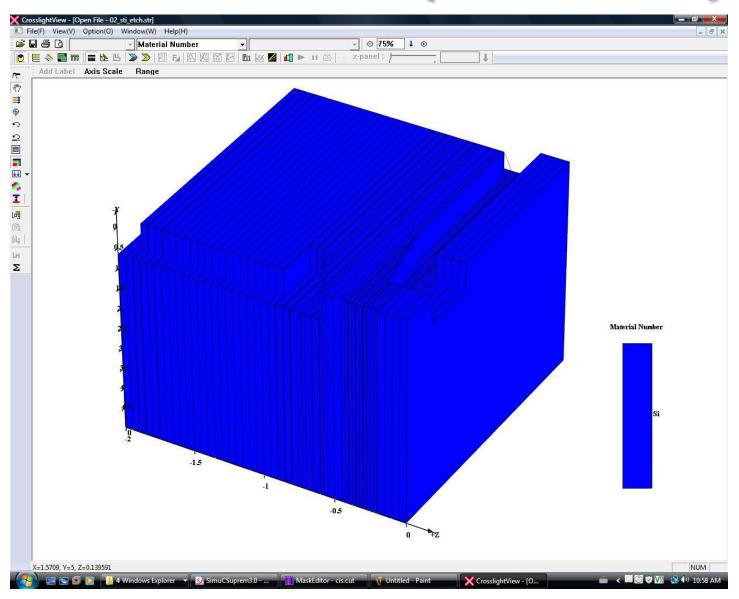
Mask Set 01 - STI







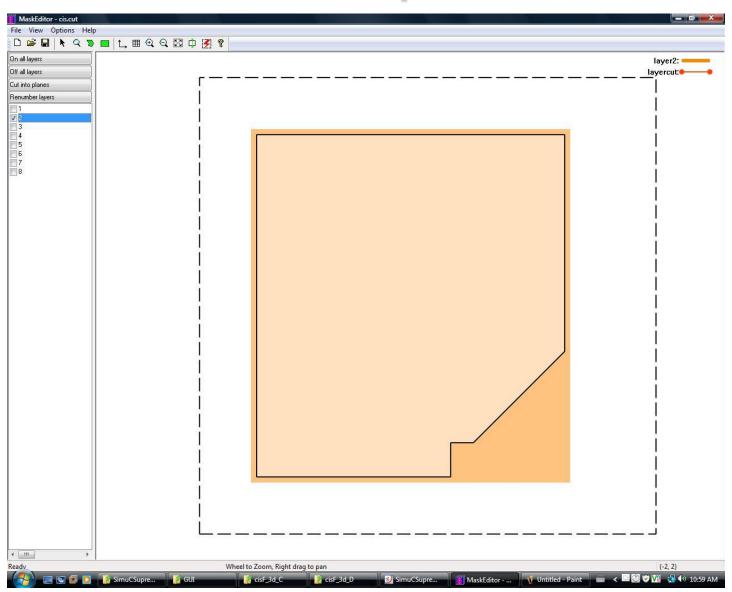
Silicon Etch for STI (Mask Set 01)







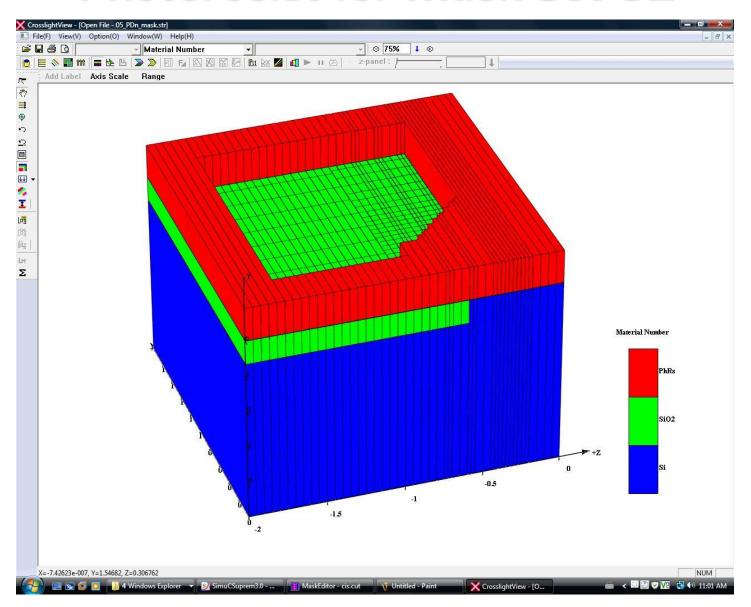
Mask Set 02 – n⁺-Implantation for PD





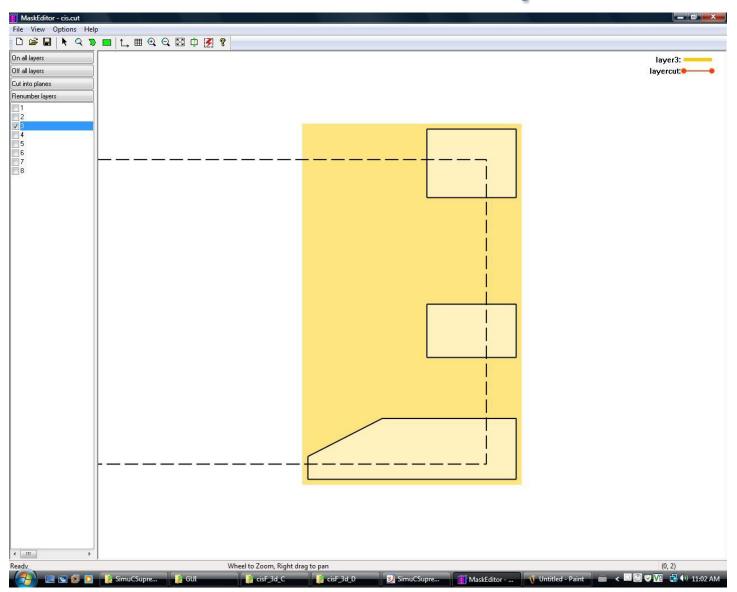


Photoresist for Mask Set 02





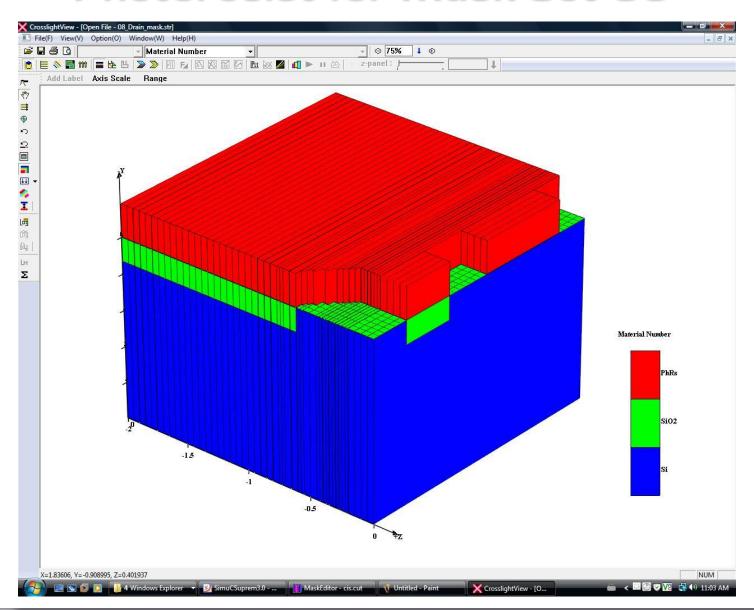
Mask Set 03 — S & D n-Implantation







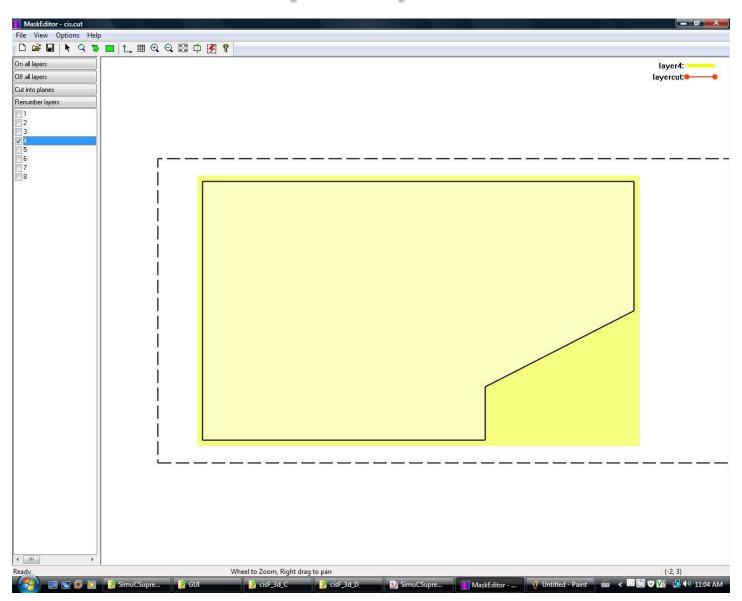
Photoresist for Mask Set 03







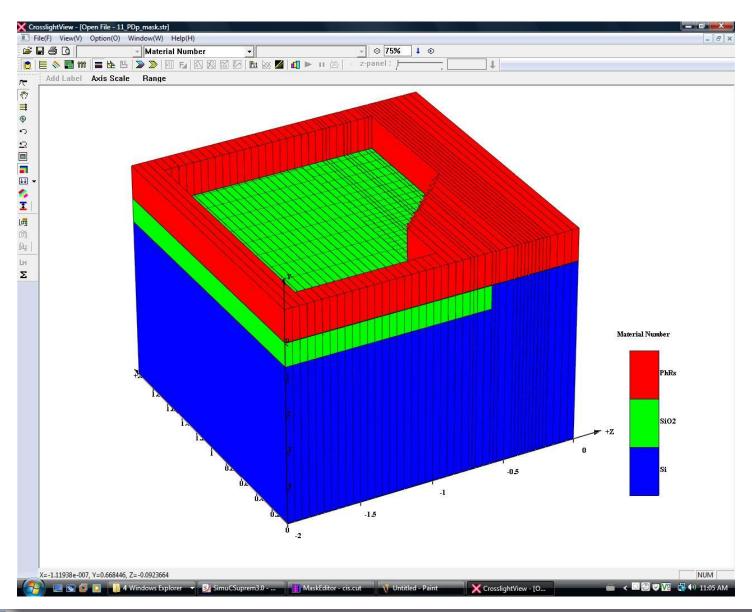
Mask Set 04 — p⁺-Implantation for PD





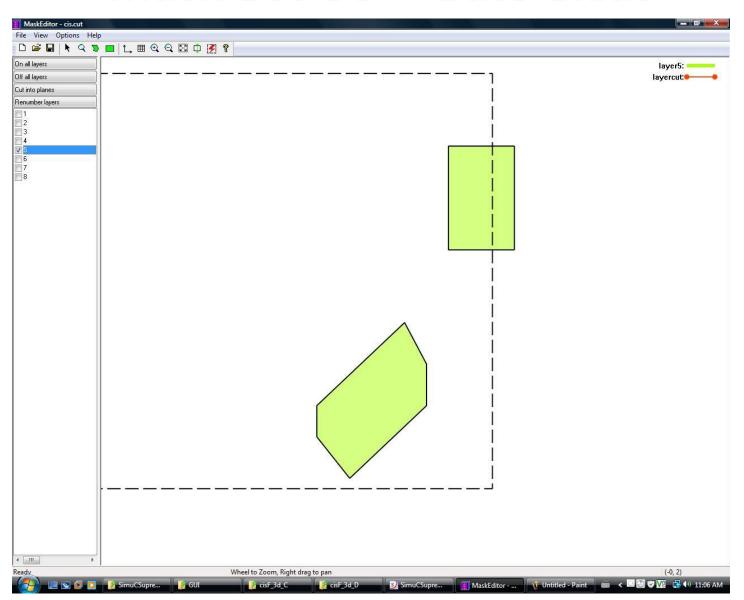


Photoresist for Mask Set 04





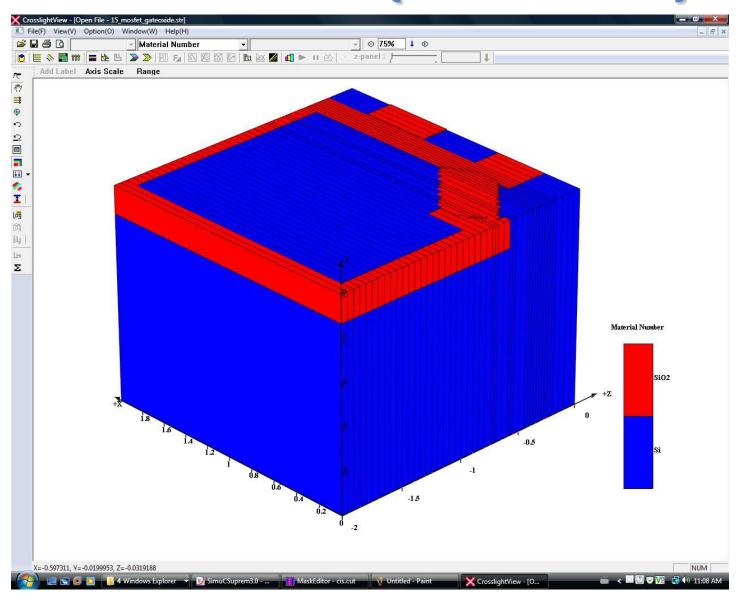
Mask Set 05 - Gate Oxide







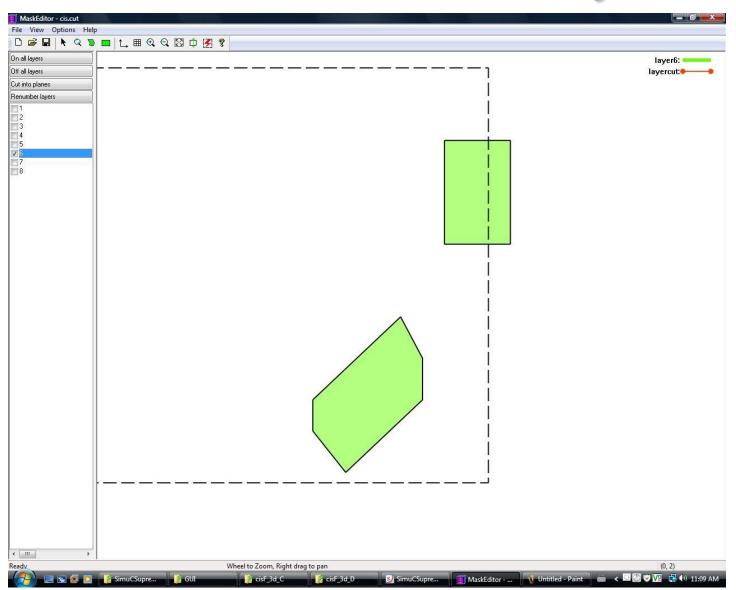
Oxide After Etch (Mask Set 05)







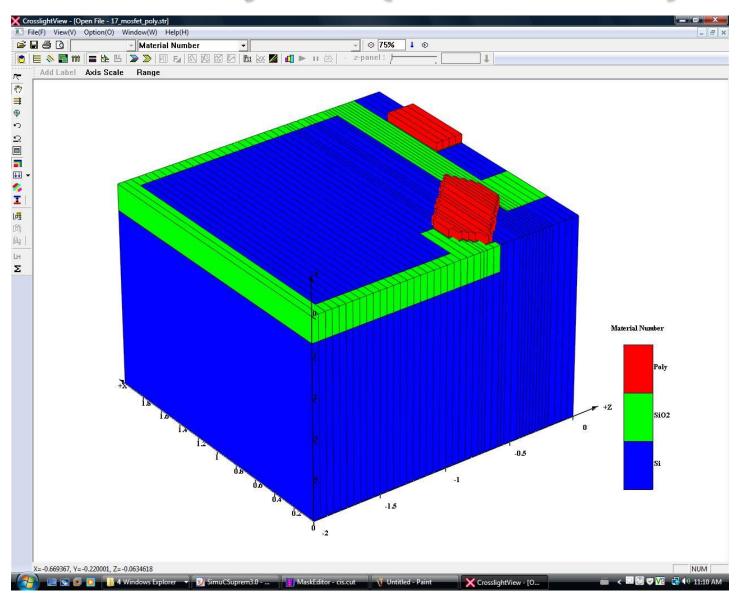
Mask Set 06 - Gate Poly Si







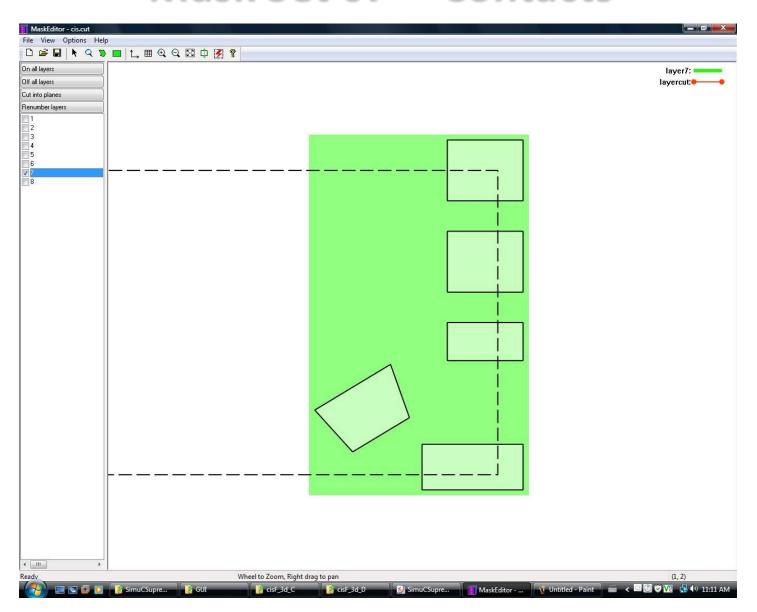
Gate Poly Etch (Mask Set 06)





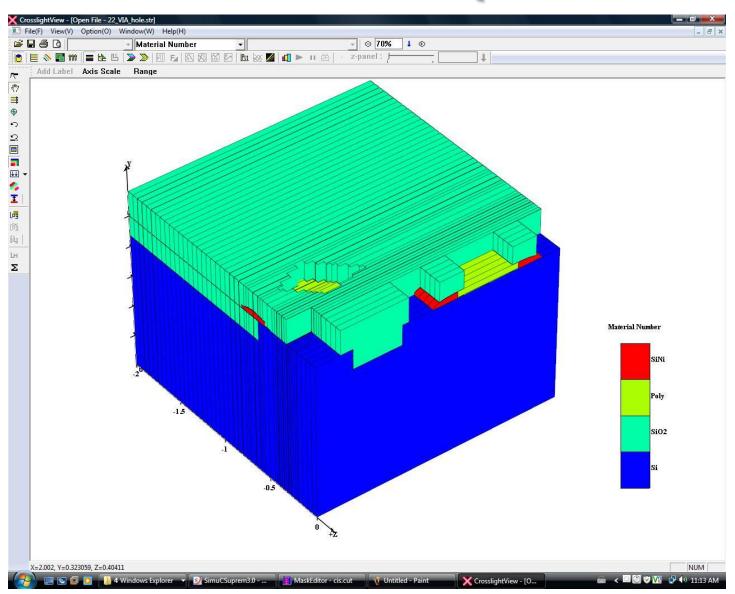


Mask Set 07 — Contacts





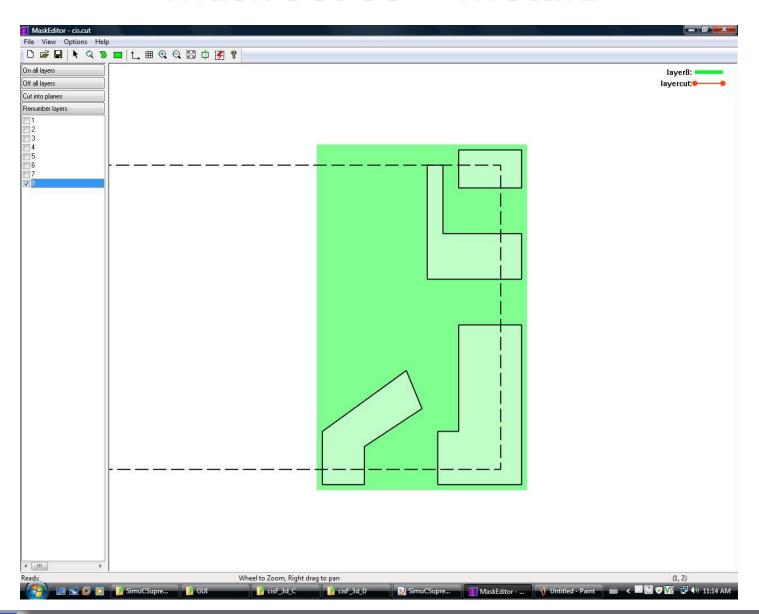
ILD1 and Contact holes (mask set 07)





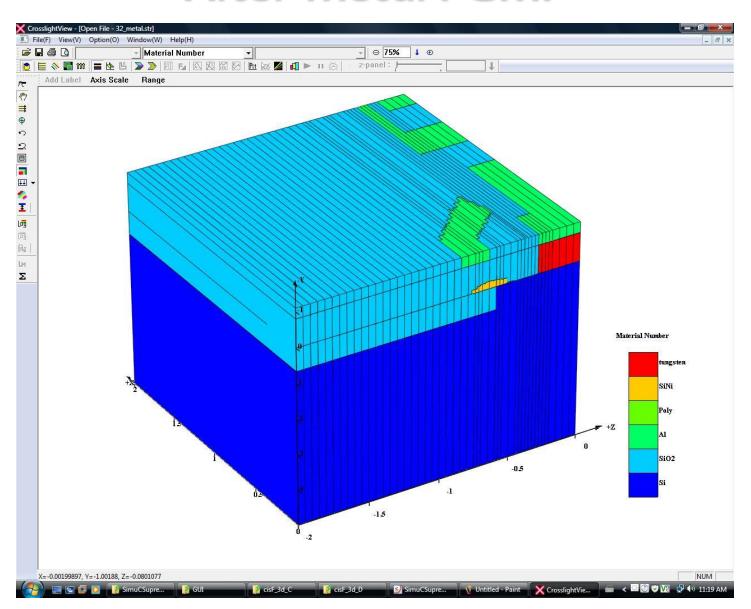


Mask Set 08 — Metal1





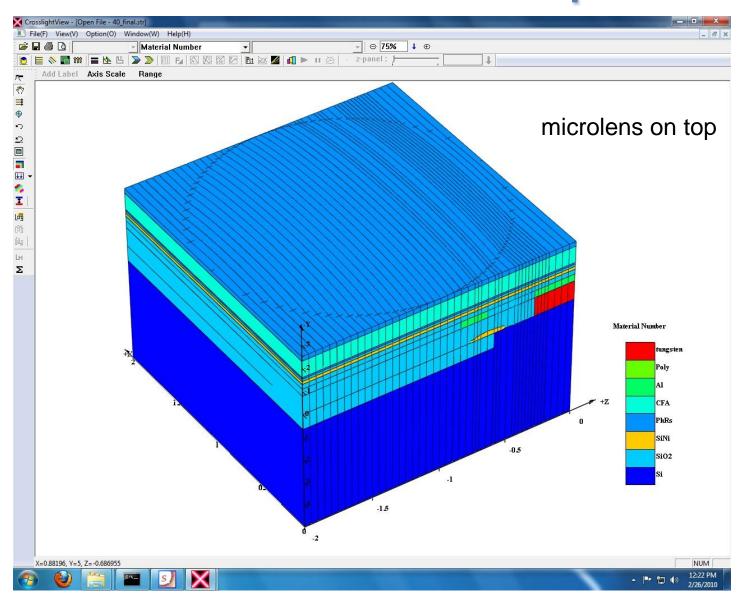
After Metal1 CMP





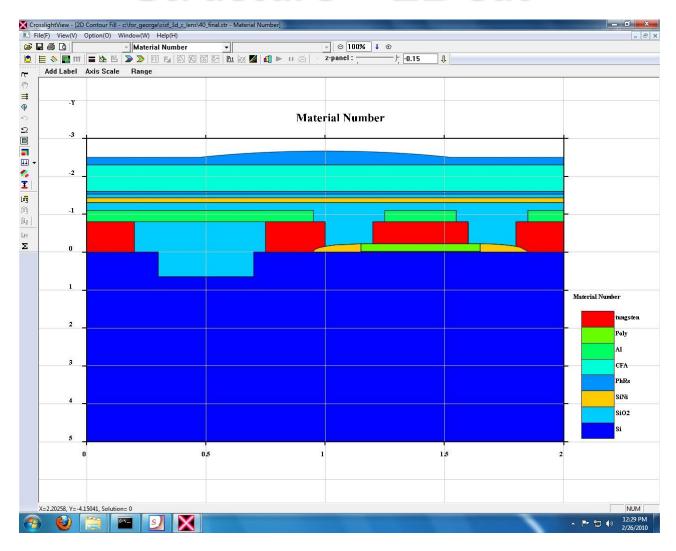


Structure after micro lens process





Structure - 2D cut

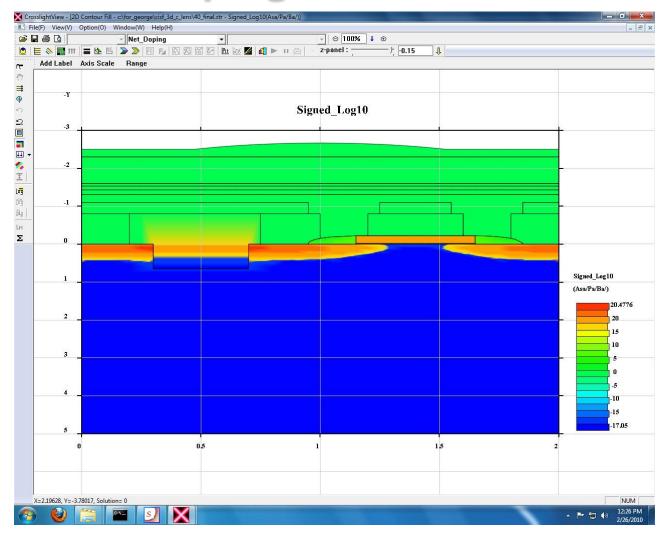


Cut along -0.15 um (corresponding to mask set Z Axis).





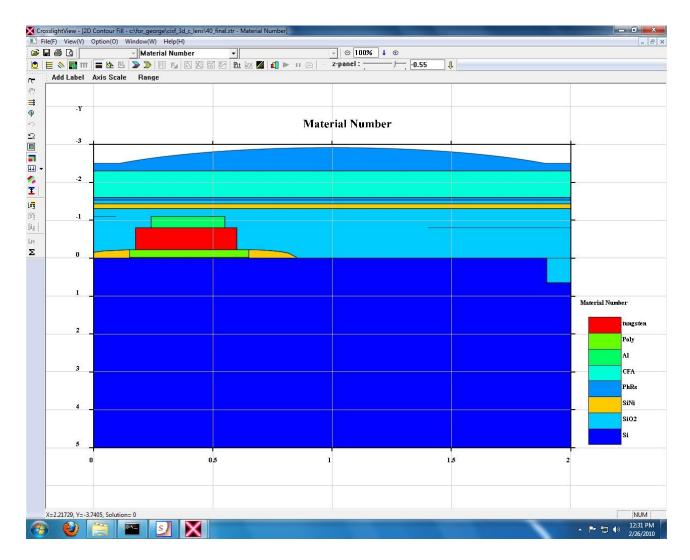
Net Doping Profile - 2D cut



Cut along -0.15 um (corresponding to mask set Z Axis).



Structure - 2D cut

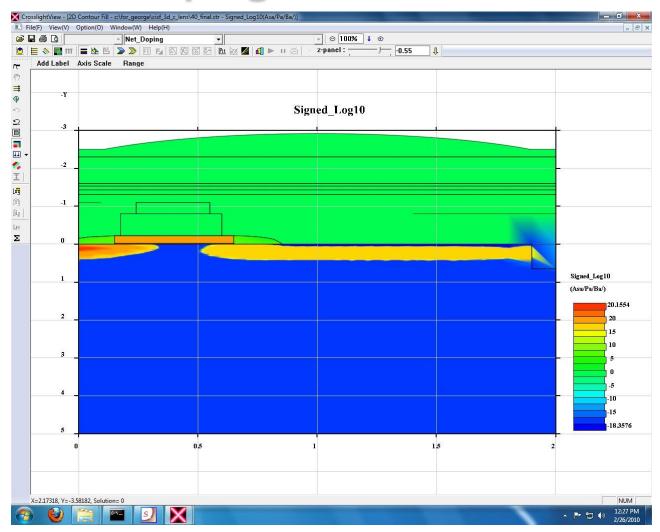


Cut along -0.55 um (corresponding to mask set Z Axis).





Net Doping Profile - 2D cut

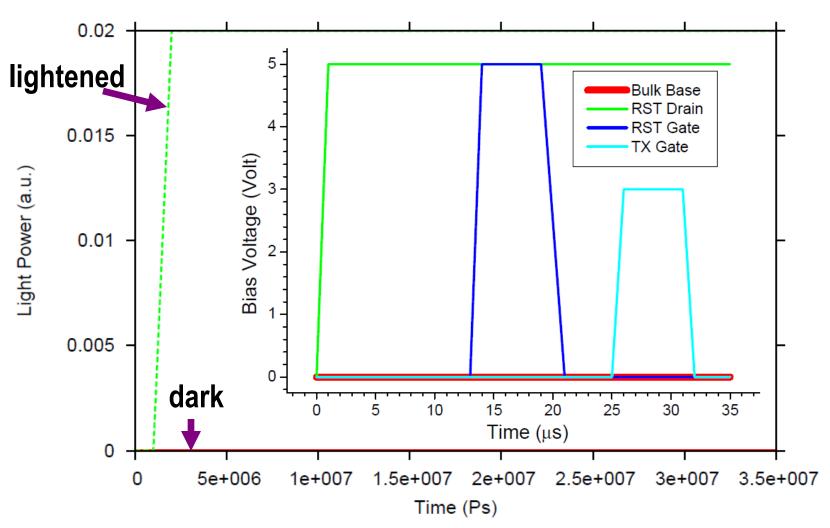


■ Cut along -0.55 um (corresponding to mask set Z Axis).





Bias Clocking

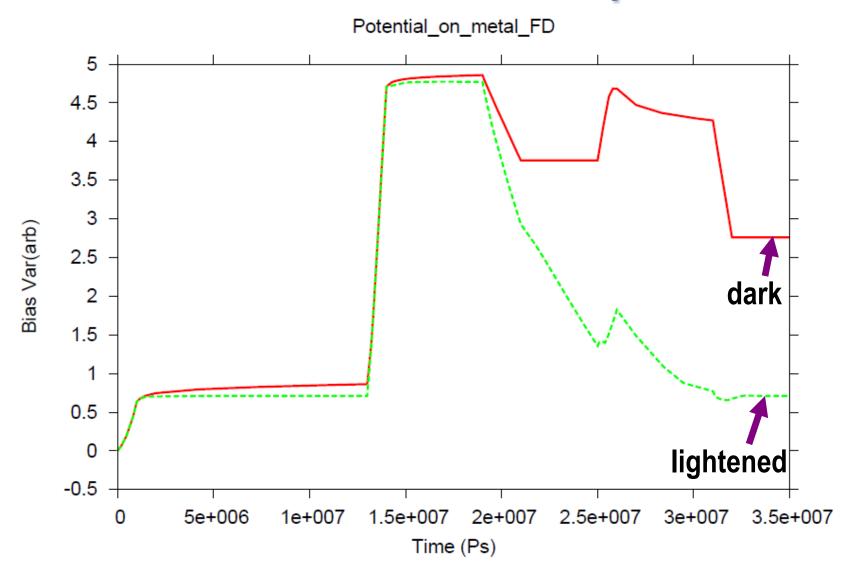


Light power base unit is 5x10⁴ W/m².





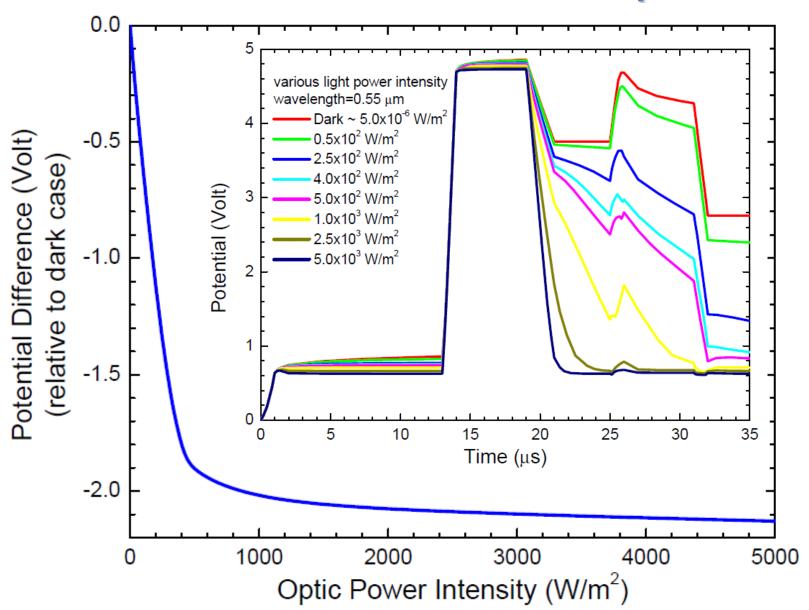
Results — Potential Comparison







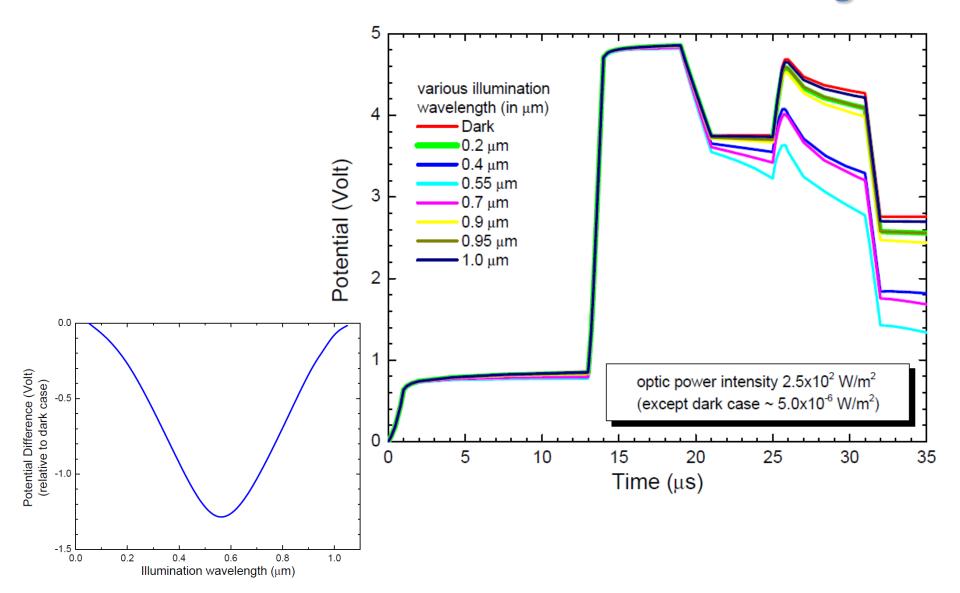
Results — Potential Difference vs. Optic Power



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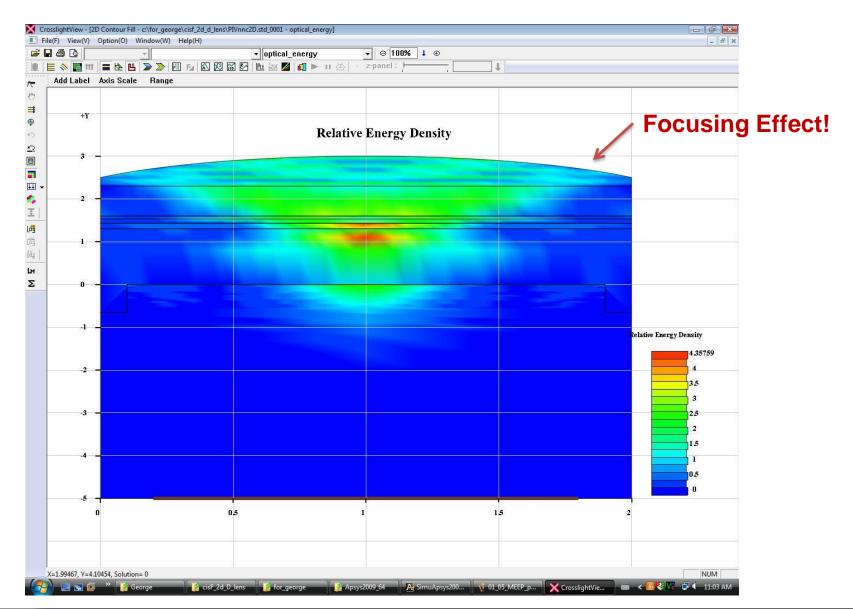
Results — Potential Difference vs. Wavelength







Initial Results for 2D FDTD Simulation with Lens





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